

00862.022172



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)	
	:	Examiner: K. Nguyen
Yasuhiro SHIMADA et al.	)	
	:	Group Art Unit: 2881
Application No.: 09/819,669	)	
	:	Confirmation No.: 3218
Filed: March 29, 2001	)	
	:	Allowed: May 6, 2004
For: ELECTRON OPTICAL SYSTEM ARRAY,	)	
METHOD OF FABRICATING THE SAME,	:	July 9, 2004
CHARGED PARTICLE BEAM EXPOSURE	)	
APPARATUS, AND DEVICE	:	
MANUFACTURING METHOD	)	

**Mail Stop Issue Fee**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

LETTER TRANSMITTING CORRECTED FORMAL DRAWINGS

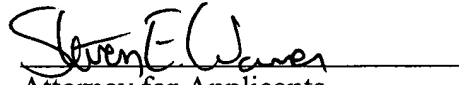
Sir:

Transmitted herewith are two (2) formal drawing sheets, corrected Figures 12 and 13, to be substituted for the corresponding drawing sheets currently on file in the above-identified application.

Figures 12 and 13 incorporate the changes requested by Applicants in a Request for Approval of Drawing Change filed June 10, 2003, which was subsequently approved by the Examiner in the Notice of Allowability dated May 6, 2004.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address listed below.

Respectfully submitted,

  
Attorney for Applicants  
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